

**PATENT**

Att. Dkt. No.: AMAT/5619/DSM/LOW K/JW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:  
Nguyen, et al.**

Serial No.: 09/912,103

**Confirmation No.: 4476**

**Filed: July 23, 2001**

**For: Selective Etching of Organosilicate  
Films Over Silicon Oxide Stop Etch  
Layers**

**MAIL STOP AF**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

**Dear Sir:**

www.pearsoned.com

**Group Art Unit: 2823**

**Examiner:** Khiem D. Nguyen

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**CERTIFICATE OF FAX**  
**37 CFR 1.8**

I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number 703-872-9306 to the attention of the named Examiner, on the date below.

1/6/05  
Date

Signature \_\_\_\_\_

## STATEMENT OF COMMON OWNERSHIP

The present application (Serial No. 09/912,103; hereinafter the "Application"), and, Patent No. 6,777,171, *Xu et al.*, were, at the time the invention of the Application was made, owned by the same person, or subject to an obligation of assignment to the same person, Applied Materials, Inc.

Respectfully submitted,

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## Keith M. Tackett

**Registration No. 32,008**

**MOSEY, PATTERSON & SHERIDAN, L.L.P.**

3040 Post Oak Blvd., Suite 1500

Houston, TX 77056

Telephone: (713) 623-4844

**Facsimile:** (713) 623-4846

Attorney for Applicant(s)